

## MODEL 1080

## PicoMill® TEM specimen preparation system

Combines an ultra-low energy, inert gas ion source and a scanning electron column with multiple detectors to yield optimal TEM specimens.

Model 1080 PicoMill® TEM specimen preparation system specifications	
Applications	Primary: Microelectronics and semiconductor transmission electron microcopy (TEM) specimen preparation
	Secondary: Any other specimens requiring optimal results
	Ideal for when FIB preparation is combined with aberration corrected TEM
lon source	Filament-based ion source combined with electrostatic lens system
	Variable voltage (50 eV to 2 kV), continuously adjustable
	Beam current density up to 8 mA/cm <sup>2</sup>
	Beam size < 1 µm
Electron source	Accelerating voltage up to 15 keV
	Working distance of 16 mm
	Faraday cup for electron beam current monitoring with a range of 1 to 2,000 pA
Goniometer	TEM style
	X, Y, and Z axes movement and $\alpha$ tilt
	Specimen exchange of < 30 seconds
	Milling angle range of $-15$ to $+90^{\circ}$
	Viewing range -15 to 180°
Holder	Side-entry, TEM-style holder
	Single-tilt with ±20° in-plane rotation
lon beam targeting	lon beam can be targeted to a specific point on the specimen surface or scanned within a selected area
User interface	Menu-driven with system status displayed

## MODEL 1080 PicoMill® TEM specimen preparation system

Gas	lon source gas: UHP 99.999% argon Gas control: Automated using mass flow control technology Pneumatic supply: Compressed dry air or dry nitrogen at 2 to 7 bar
Imaging	Secondary electron detector/Everhart-Thornley detector  • Electron imaging with 2 mm field of view  • Ion-induced secondary electron imaging with 1.9 mm field of view  • Specimen image displayed on PicoMill system user interface  Solid-state backscatter electron detector  Solid-state scanning/transmission electron (STEM) detector
Vacuum system	Turbomolecular drag pump backed by an oil-free diaphragm pump  Specimen chamber pressure:  Base vacuum of 3 x 10 <sup>-6</sup> mbar  Operating vacuum of 1 x 10 <sup>-4</sup> mbar  Electron column: Base vacuum of 1 x 10 <sup>-6</sup> mbar  Specimen goniometer: Atmosphere to 1 mbar (pre-pump)  Vacuum gauges:  Cold cathode for specimen chamber and electron column  Pirani gauge for goniometer
Automatic termination	Termination by time, electron signal, or manual process
Dimensions	80.75 in. [205.51 cm] width x 57.85 in. [146.94 cm] height x 50.13 in. [127.33 cm] depth
Weight	500 lbs. [227 kg]
Power	208-240 VAC, 50/60 Hz, 1,100 W
Warranty	One year
Service contract	Download service contract information

<sup>\*</sup>Standard side-entry TEM specimen holders cannot be used in the PicoMill system because they do not provide access to the specimen for ion milling. However, the PicoMill system holder can be used in both the PicoMill system and in corresponding electron microscopes.



